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P.O. BOX 506, Merrifield, VA 22116, U.S.A.

Voice Mail: 302-729-1562 FAX: 806-498-6673 e-mail: winstonhsu@naipo.com

FAX TO : SUN, XIUQIN

ART UNIT: 2863

TEL : (571) 272-2280

FAX: (571) 273-8300

FROM : Winston Hsu, PATENT AGENT, REG. NO. : 41,526

SERIAL NO. : 10/708,783

ATTORNEY DOCKET NO.: LKSP0026USA

SUBJECT: Applicant Initiated Interview Request Form

TOTAL PAGES : 2 PAGES (INCLUDING COVER PAGE)

Scott Margo **APR 25 2006**

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PTOL-413A (09-04)
Approved for use through 07/31/2008. OMB 0851-0031
U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE**Applicant Initiated Interview Request Form**Application No.: 10/708,783 First Named Applicant: Long-Hui Lin
Examiner: Sun, Xiuqin Art Unit: 2863 Status of Application: After Final**Tentative Participants:**(1) Scott Margo # 56,277 (2) Examiner Sun, Xiuqin
(3) _____ (4) _____Proposed Date of Interview: April 25, 2006 Proposed Time: 11:00AM (AM/PM)**Type of Interview Requested:**(1) ☒ Telephonic (2) ☐ Personal (3) ☐ Video ConferenceExhibit To Be Shown or Demonstrated: ☐ YES ☒ NO

If yes, provide brief description: _____

Issues To Be Discussed

Issues (Rej., Obj., etc)	Claims/ Fig. #s	Prior Art	Discussed	Agreed	Not Agreed
(1) <u>Rejection of</u>	<u>claim 8</u>	<u>Pinto et al.</u>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
(2) _____	_____	_____	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
(3) _____	_____	_____	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
(4) _____	_____	_____	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
<input type="checkbox"/> Continuation Sheet Attached					

Brief Description of Arguments to be Presented:

In paragraph [0078], Pinto teach that a "test structure" is formed on the substrate. Therefore, Pinto

teaches performing defect inspections on monitor wafers, and not on product wafers, as is claimed.

The claimed method does not require the use of extra monitor wafers, lowering the manufacturing cost.

An interview was conducted on the above-identified application on _____.

NOTE: This form should be completed by applicant and submitted to the examiner in advance of the interview (see MPEP § 713.01).

This application will not be delayed from issue because of applicant's failure to submit a written record of this interview. Therefore, applicant is advised to file a statement of the substance of this interview (37 CFR 1.133(b)) as soon as possible.

Scott Margo APR 25 2006
Applicant/Applicant's Representative Signature_____
Examiner/SPE SignatureScott Margo

Typed/Printed Name of Applicant or Representative

56,277

Registration Number, if applicable

This collection of information is required by 37 CFR 1.133. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.11 and 1.14. This collection is estimated to take 21 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.